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PATENT #42 NEAL

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Applicants : Ulrich C. Boettiger and Scott L. Light
Application No. : 09/945,316 Confirmation No.: 1351
Filed : August 30, 2001
For : METHOD AND APPARATUS FOR CONTROLLING
RADIATION BEAM INTENSITY DIRECTED TO
MICROLITHOGRAPHIC SUBSTRATES

Docket No. : 108298547US

Date : December 31, 2001

Commissioner for Patents
Washington, DC 20231

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PRELIMINARY AMENDMENT

Dear Commissioner:

In keeping with 37 C.F.R. § 1.121, this paper includes a clean version of the amended specification paragraph. An appendix is attached showing the marked-up version of the specification paragraph amended in the present response. Please amend the application as follows and reconsider the application in light of the following remarks.

A